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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re:	Detlef Michelsson	Confirmation No:	5672
Serial No:	10/772,510	Group:	2609
Filed:	February 5, 2004	Examiner:	Fujita, Katrina R
For:	Method and Apparatus for Examining Semiconductor Wafers in a Context of DIE/SAW Design		
Customer No.:	29127		
Attorney Docket No.	21295.74US (H5742US)		

**AMENDMENT AND REPLY**

VIA FACSIMILE: 571-273-8300  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

In response to the pending Office Action, mailed February 5, 2007, please amend the above-captioned application as follows:

- amendments to the specification are set forth in section a);
- amendments to the claims are reflected in the listing of claims in section b);
- and finally, reconsideration is requested in view of the remarks set forth in section c).